

POSITION FINDING APPARATUS FOR WAFER, POSITION FINDING METHOD, AND
WAFER SPEED COUNTING METHOD

ABSTRACT

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Disclosed is a position finding apparatus for a wafer. The wafer is in a rotating state, and the outer edge of the wafer is provided with a notch part. The position finding apparatus at least comprises: a signal transmitting mechanism used for transmitting a signal to a direction where the wafer is located, the signal being able to pass through the notch part, and the signal being blocked
10 by the wafer when passing through the wafer; and a signal receiving mechanism used for receiving the signal transmitted by the signal transmitting mechanism so as to determine whether the notch part passes through the signal transmitting path or determine the number of times that the notch part passes through the signal transmitting path. Further disclosed is a wafer position finding method. Further disclosed is a wafer rotating speed counting method. According to the present
15 invention, wafer positioning is realized, the position of the notch part of the wafer can be determined, the wafer taking/placing reliability in the processes is improved, the space of a device is saved, and the wafer rotating speed measurement reliability is improved.

FIG. 1